

TRANSLATION FROM JAPANESE

- (19) JAPANESE PATENT OFFICE (JP)
- (12) Official Gazette for Unexamined Utility Model Applications (U)
- (11) Unexamined Utility Model No. **58-146346**
- (43) Disclosure Date: Oct. 1, 1983

		Internal Office
(51)	<u>Int. Cl.⁴:</u>	<u>Classification Symbols:</u>
	H01J 37/20	7129-5C
	37/18	7129-5C

Request for Examination: Not filed

(Total of 1 page [in original])

(54) Title of the Invention: **Sample exchange device for scanning electron microscope**

- (21) Application No.: 57-42991
- (22) Filing Date: Mar. 26, 1982
- (72) Inventor: ISHIMORI Yoshio
- (72) Inventor: SHIBUKI Yoichi
- (71) Applicant: NIPPON DENSHI KK

(57) Claims

Sample exchange device for scanning electron microscope, [said device]
comprising a plurality of sample exchange chambers arranged in communication with a

sample chamber and a vacuum valve; and means for preliminary evacuation of each individual sample exchange chamber, and designed such that while a sample exchange chamber is being subjected to preliminary evacuation in preparation for introduction of a sample into the sample chamber via said sample exchange chamber, another sample may be observed.

Brief Description of the Drawings

The drawing illustrates an embodiment of the invention.

1: lens barrel; 2: sample chamber; 3: stage; 4a, 4b: sample exchange chambers; 5a, 5b, 6a, 6b, 12a, 12b, 13a, 13b, 14, 15, 16, 17, 18: vacuum valves; 7a, 7b: sample exchange rods
11: rotary pumps; 9a, 9b: evacuation lines; 10: diffusion pump; Ha, Hb: sample holders.

公開実用 昭和 58—146346

19 日本国特許庁 (JP)

11 実用新案出願公開

12 公開実用新案公報 (U)

昭58—146346

51 Int. Cl.³
H 01 J 37 20
37 18

識別記号

庁内整理番号
7129—5C
7129—5C

43 公開 昭和58年(1983)10月1日

審査請求 未請求

(全 頁)

54 走査電子顕微鏡等の試料交換装置

株式会社内

72 考案者 洪木洋一

昭島市中神町1418番地日本電子
株式会社内

21 実 願 昭57—42991

22 出 願 昭57(1982)3月26日

73 考案者 石森能夫

昭島市中神町1418番地日本電子

71 出 願 人 日本電子株式会社

昭島市中神町1418番地